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LSE-MS Microspot System

Shown with optional LRS 6 inch linear x 360° rotary stage above

stokes microspot ellipsometer LSE-MS description

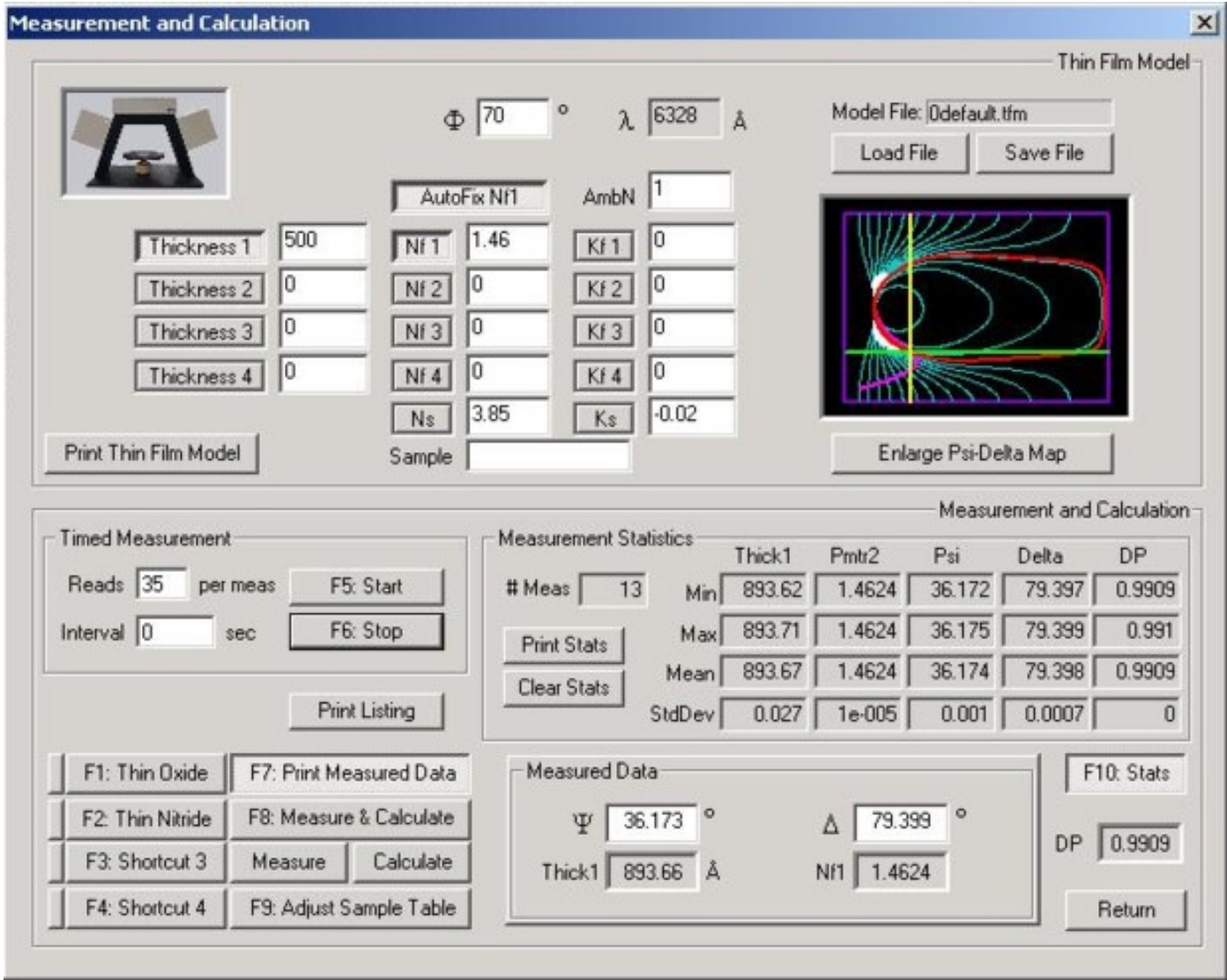
Has a 15 micron measuring laser beam diameter, manual XY micrometer positioning stage and camera for viewing the measurement area on your PC. Areas as small as 15 X 45 micron can be measured. The units' simple yet robust design offers ease of use and instantaneous measurement and is a welcome alternative to overly complicated ellipsometers.

The LSE-MS ellipsometer uses advanced [StokesMeter™](#) technology (previous winner of Photonics Spectra and R&D 100 best new products awards) with no moving parts and no modulators to quickly and accurately determine the complete polarization state of the 6328Å laser measuring beam at a 70° incidence angle. The laser light source has ample light intensity for increased measurement accuracy of absorbing and rough scattering films. Laser sources have the added advantage of being spectrally precise, stable and long lasting. Their use permits optimum instrument design in optics, detectors and other components so that measurements can be made highly accurate. The space-saving design features a small footprint yet it can accommodate large samples up to 300mm wide. The sample table includes a manual tilt and table height adjustment which is set using an alignment screen on the computer.

high speed film thickness measuring system measures in less than a second!

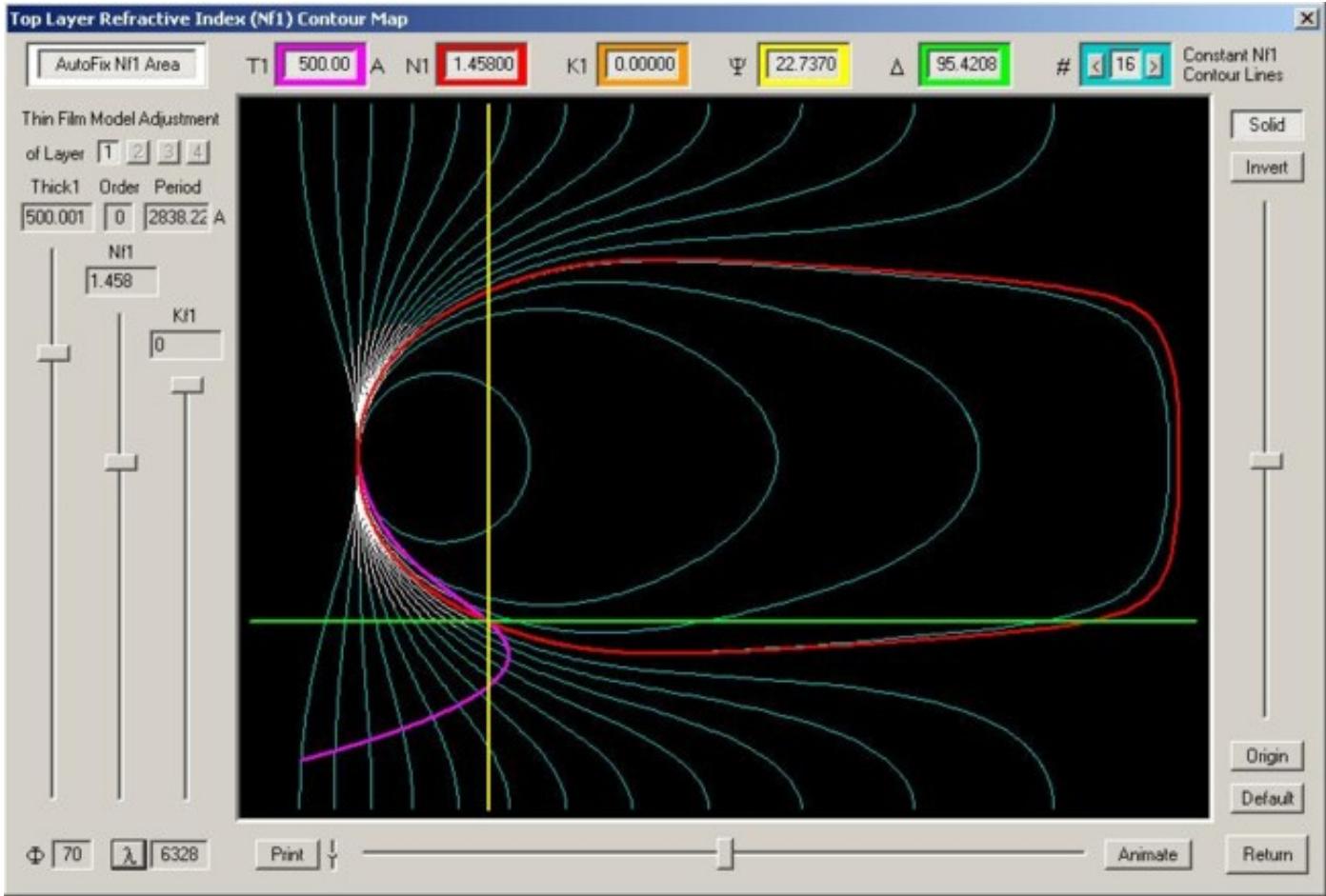
features

- Trouble-free, no moving parts advanced [StokesMeter™](#) measurement head.
- Measures complete state of polarization providing increased accuracy.
- Accurate, stable measurements using spectrally precise laser ellipsometry.
- Fastest possible instrument for thin film measurement.
- Tilt-free, focus free, hands-off operation for similar wafers.
- Simple, compact tabletop instrument - competitively priced.



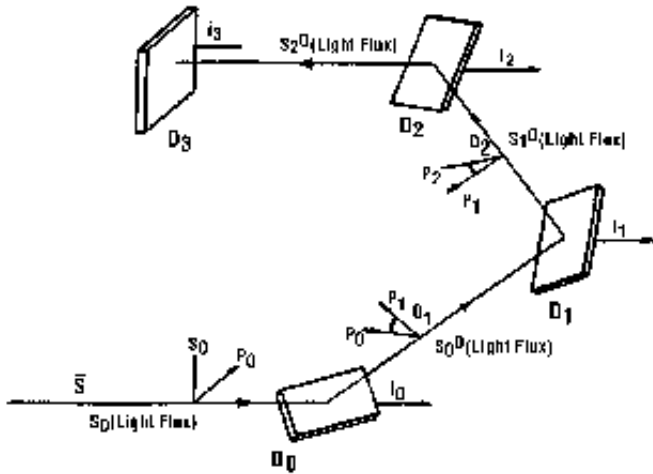
gaertner ellipsometer measurement program LGEMP description
The LGEMP Windows software is versatile and can measure single layer films such as oxides, nitrides and photoresists as well the top layer on a known 1, 2, or 3 layer stack such as poly on oxide and oxide on poly on oxide. Monolayer organic films are an excellent application for the precision and stability of the model LSE.

A "File Handler" enables saving and quick retrieval of frequently used measurement setup parameters. Four user-defined setup files can be assigned to one step "press-and-go" shortcut buttons for fast access of different measurement setups.



The **Enlarged PSI-Delta Map** from within the LGEMP program permits theoretical "what if" type simulation of your Thin Film Model; giving a deeper understanding to the film model. The top layer film Thickness T1 (pink line), Refractive index Nf1 (red line), Absorption Kf1 (brown line), Y (yellow line), D (green line), with moveable sliders on the left side quickly show the effects of varying the model parameters on the film refractive index resolution and measurability. The aqua color lines are lines of constant film refractive index Nf1. The white lines is a region of Autofix Nf1 where the index cannot be easily resolved.

description of stokesmeter™ technology
This advanced device uses no moving parts and no modulators to quickly and accurately determine the complete polarization state of the measuring beam.



The diagram above shows the [StokesMeter™](#) photopolarimeter for the simultaneous measurement of all four Stokes parameters of light. The light beam, the state of polarization of which is to be determined, strikes, at oblique angles of incidence, three photodetector surfaces in succession, each of which is partially spectrally reflecting and each of which generates an electrical signal proportional to the fraction of the radiation it absorbs. A fourth photodetector is substantially totally light absorptive and detects the remainder of the light. The four outputs thus developed form a 4x1 signal vector **I** which is linearly related, **I=AS**, to the input Stokes vector **S**. Consequently, **S** is obtained by **S=A(-1)I**. The 4x4 instrument matrix **A** must be nonsingular, which requires that the planes of incidence for the first three detector surfaces are all different. For a given arrangement of four detectors, **A** can either be computed or determined by calibration.

technological advantage

The simple, compact [StokesMeter™](#) replaces a typical rotating analyzer assembly consisting of a drum, prism, encoders, switches, motor and detector and their associated electronics. In addition, the waveplate mechanism on the polarizer arm, is eliminated resulting in a fast, precise, no moving parts ellipsometer.

An outstanding feature is the Stokes Ellipsometer's compensation for small changes in angular beam deviation caused by sample out-of-flatness; thus permitting fast, uninterrupted measurement over the entire wafer surface without the need to pause to correct for focus and tilt. .

Extremely precise and stable the model LSE-MS Stokes Ellipsometer is an excellent value in a basic uncomplicated ellipsometer. The LSE-MS model ellipsometer ships complete with LGEMP Windows™ software, USB cables, XY sample stage and reference wafer. It interfaces to your Windows™ PC or Laptop with 2 USB 2.0 ports.

LSE- MS can be equipped with the following options:

Optional Linear Rotary Sample Stage LRS

6 inch linear and 360 degree rotary stage in place of standard sample stage

Optional WIN 10 Laptop PC

With preloaded drivers and software and security cable

Optional Stokes Calibration Kit L118-KIT

Recalibrate any Stokes Ellipsometer using 4 Gaertner traceable wafers plus glass \$ 2 K (L118G-KIT) or 4 NIST traceable wafers plus glass \$ 3.5 K (L118N-KIT). Most users will not require ellipsometer recalibration. Intended for the most exacting semiconductor manufacturers with extremely tight tolerances and regulatory compliant users.

stokes ellipsometer LSE-MS specifications

Alignment:	Manually adjusted tilt and table height using computer alignment screen.
Camera	Shows measurement area on your PC
Incidence Angle:	70°
Method of Measurement:	Advanced StokesMeter determines the complete measuring beam polarization using no moving parts and no modulators, only 4 stationary silicon detectors so measurements are stable and exact.
Measurement Time:	Practically instantaneous
Measuring Laser:	6328Å HeNe Gas Laser with 15 x 45 um measuring beam diameter
Alignment Laser:	670nm Laser Diode
Sample (Wafer) Size:	accepts up to 300 mm wide X unlimited length
Stage:	XY hand positioning with tilt and table height adjustment.
Software:	Windows™ LGEMP 4 layer absorbing program included.
Required Computer:	Windows™ desktop or laptop with 2 USB 2.0 ports (not included).
Film Thickness Range:	0 - 60,000 Angstroms on substrate or on 1, 2, 3, or 4 known sublayers.
Precision & Repeatability:	Sub-Angstrom over most of the measurement range.
Refractive Index:	± .0005 over most of the measurement range.
Power:	100V-240V, 50-60Hz. 1 A
Dimensions:	Height: 16.5 Width: 27.5 Depth: 16 inches Net Weight: 45 lbs. Shipping Weight: 65 lbs.
CDRH Compliance:	All laser ellipsometers supplied by Gaertner comply with CDRH requirements 21CFR 1040 for a Class II laser product emitting less than 1 mW or Class IIIb less than 5 mW of low power radiation. As with any bright source such as the sun or arc lamp, the operator should not stare directly into the laser beam or into its reflection from highly reflecting surfaces.
CE Compliance:	Stokes Ellipsometers comply with European safety directives and carry the CE mark.

Warranty: 1 year warranty covers all parts and labor exclusive of shipping costs

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